

Fig. 1
Related Art

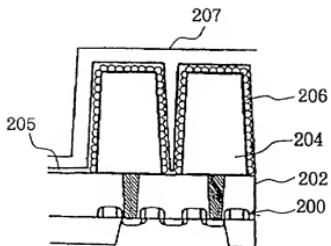
Ryo KUBOTA et al.
"Manufacturing Method of Semiconductor
Device Having Dram Capacitors"

Q62494

Filed March 27, 2001

Sheets 2 of 11

Fig. 2
Related
Art



05847233-032701

Fig. 3A
Related Art

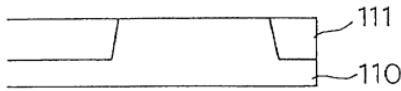


Fig. 3B
Related Art

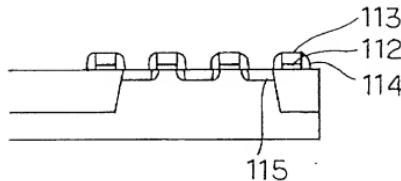


Fig. 3C
Related Art

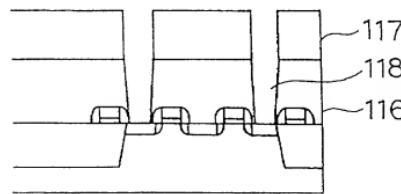


Fig. 3D
Related Art

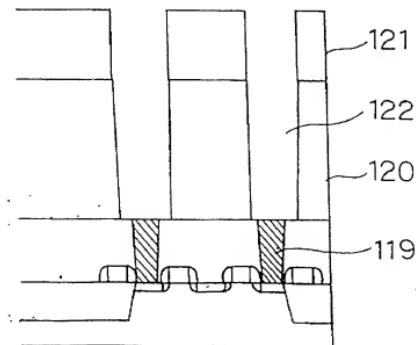


Fig. 3 E
Related Art

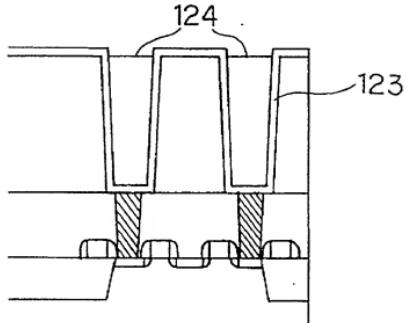
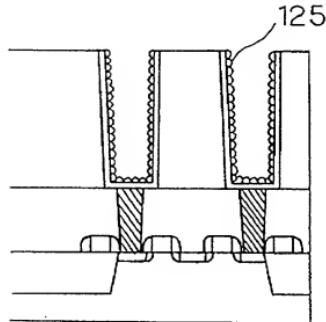


Fig. 3F
Related Art



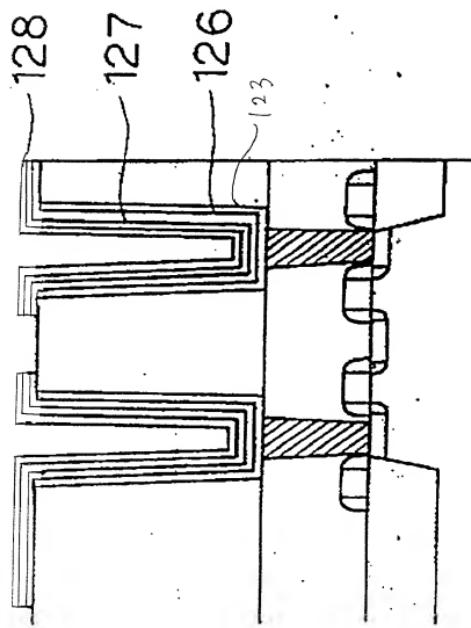


Fig. 39
Related Art

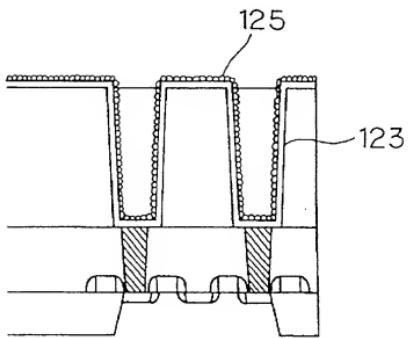


Fig. 4
Prior Art

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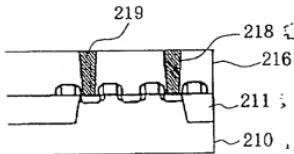


Fig. 5A

Related Art

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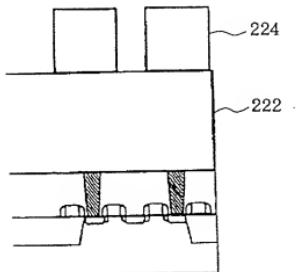


Fig. 5B

Related Art

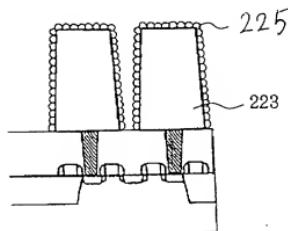


Fig. 5C

Related Art

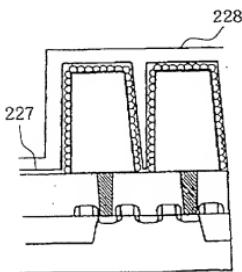
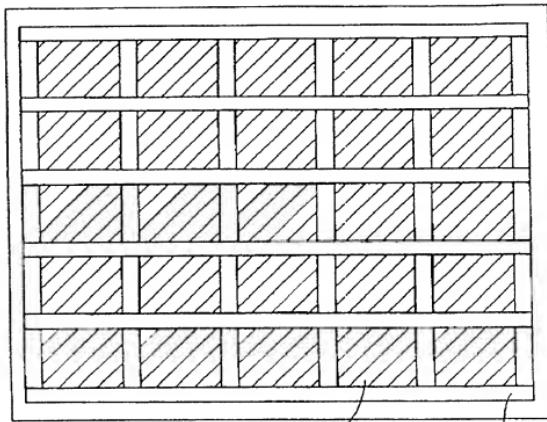


Fig. 5 D

Related Art

Fig.6A
Related
Art



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Fig.6B

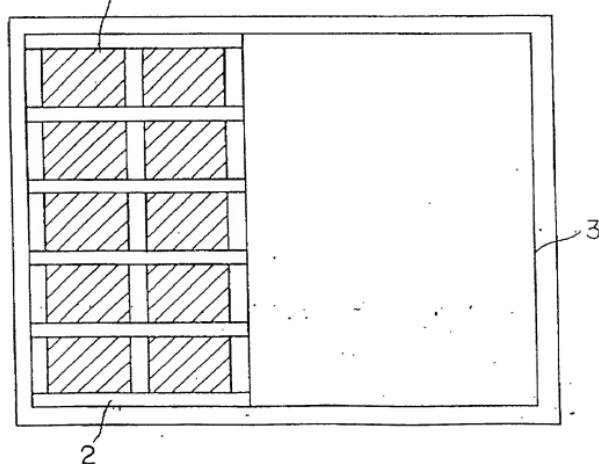


Fig. 7A

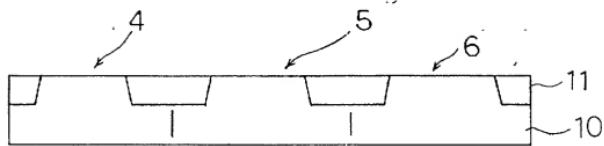


Fig. 7B

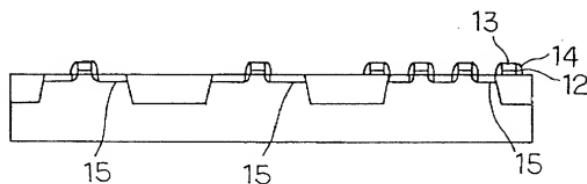


Fig. 7C

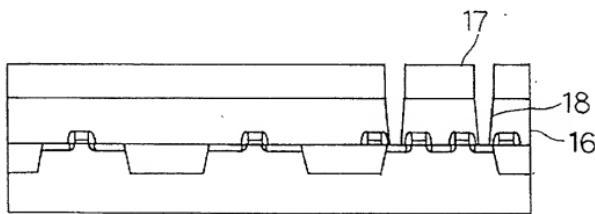
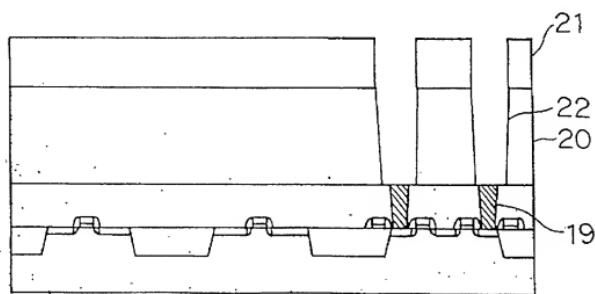


Fig. 7D



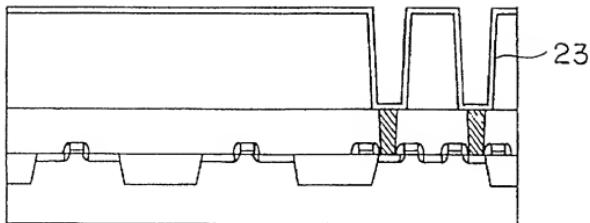
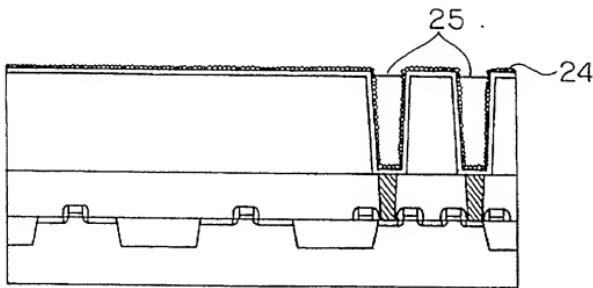


Fig. 7 E



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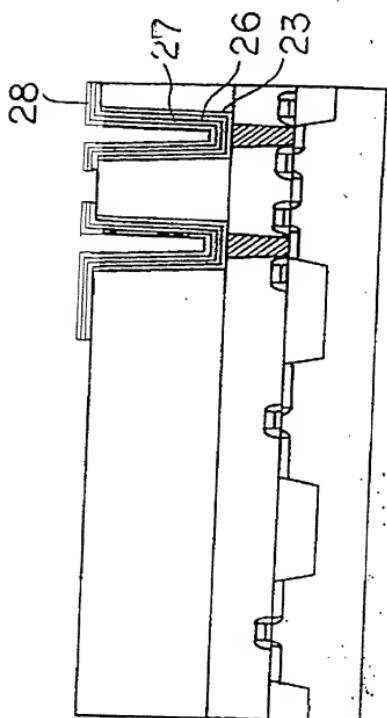


Fig. 19